



**SELDON CUSTOM PLASMAS**

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December 14, 2003

Mr. Ho Seung Chang  
President, IPS-Tech  
33 Jije-dong, Pyungtaek  
Kyungki-do, Korea

Dear Mr. Chang,

The multiple pole plasma source used by IPS-Tech and advertised in your product information as the MICP source is licensed from Seldon Custom Plasmas under an agreement signed by the previous IPS-Tech management.

This agreement gives IPS-Tech the Korean exclusive rights to manufacture the multiple pole plasma source, as long as license payments are timely sent to Seldon Custom Plasmas, under the conditions described in the agreement.

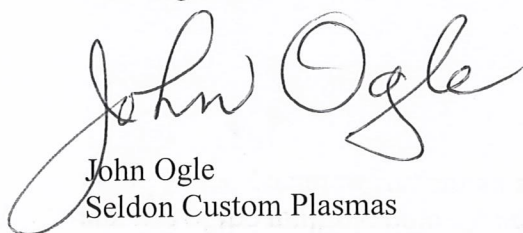
No license payments have been received for some time, and since IPS-Tech has new management, it may be necessary to confirm the relationship described in the agreement.

Please let me know whether IPS-Tech intends to continue with the agreement. If not, IPS-Tech will no longer have exclusive Korean rights to the multiple pole plasma source, and any use of the multiple pole plasma source in locations covered by the related patents will be subject to patent infringement suit.

In particular, if Samsung were to import equipment incorporating an unlicensed multiple pole plasma source to their Texas facility, they would be subject to patent infringement suit.

Seldon Custom Plasmas hopes to continue our relationship with IPS-Tech, which includes Seldon Custom Plasmas providing advice and support for solving problems and improving the MICP source, based on ongoing developments both here and in Korea.

Best regards,



John Ogle  
Seldon Custom Plasmas

비밀

## Korean Headquartered Exclusive License Rights Agreement

Integrated Process Systems, Ltd of Korea desires to have exclusive manufacturing rights to the multiple pole plasma source for companies headquartered in Korea, and Seldon Custom Plasmas of Milpitas, California, United States of America desires to grant to Integrated Process System, Ltd. these exclusive rights for companies headquartered in Korea, therefore:

Seldon Custom Plasmas agrees not to license manufacturing rights to the multiple pole plasma source to any company with headquarters in Korea other than Integrated Process Systems, Ltd., provided conditions 1 and 2 listed below are met. The rights are those described in United States patent # 5,435,881, APPARATUS FOR PRODUCING PLANAR PLASMA USING VARYING MAGNETIC POLES, and United States patent # 5,944,942, VARYING MULTIPOLE PLASMA SOURCE.

### Conditions:

- 1) The license agreement between Seldon Custom Plasmas and Chung Song Systems, Ltd, signed June 3, 1997, has not been terminated by actions described in that license agreement.
- 2) There is not an interval of a year in which Integrated Process Systems does not purchase license labels for the multiple pole plasma source, as described in that license agreement.

signed

*John Seldon Ogle*

Seldon Custom Plasmas

date

*May 8, 2000*

비밀

Seldon Custom Plasmas  
P.O. Box 334  
Milpitas, California 95035  
email: scusplas@ix.netcom.com  
May 9, 2000

Mr. Yong Han Lee, President  
Integrated Process Systems  
33 Jije-Dong  
Pyungtaek City  
Kyungki-Do, Korea

Dear Mr. Lee,

Mr. Hee Kook Park of IPS has suggested that I present to you a signed agreement that no manufacturing license will be issued to any company with headquarters in Korea other than IPS, for plasma sources using the technology described in US patent # 5,435,881, APPARATUS FOR PRODUCING PLANAR PLASMA USING VARYING MAGNETIC POLES.

The agreement is enclosed, with two conditions, first that the license agreement with Chung Song Systems, Ltd., signed June 3, 1997, has not been terminated by one of the four conditions listed in the license agreement, and second, that no period of a year will pass without purchase of license labels by IPS.

It may be desirable to revise the license agreement to incorporate the following changes:

- 1) The name of your company has changed from Chung Song Systems to Integrated Process Systems.
- 2) Related United States patent # 5,944,942, VARYING MULTIPOLE PLASMA SOURCE, has been granted on August 31, 1999, and I have informally agreed to include rights under this patent in the license agreement. This addition can be included in a revised license agreement.
- 3) The agreement not to license the multiple pole source to any other company headquartered in Korea, with the conditions listed above.

If you would like I will write up a revised license agreement for your consideration.

In addition I would appreciate an explanation of the license payment procedure in which IPS reduces the license payments by 16.5% for Korean taxes. Such license payments in the United States are not reduced by the government taxes. Is there a procedure for Seldon to recover the portion of the license costs withheld for Korean taxes?

Sincerely yours,

*John Seldon Ogle*  
John Seldon Ogle  
Seldon Custom Plasmas